

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): ANDREI V. SHCHEGROV ET AL.
Assignee: KLA-TENCOR TECHNOLOGIES CORPORATION
Title: PARAMETRIC PROFILING USING OPTICAL SPECTROSCOPIC SYSTEMS
Serial No.: 09/741,663 Filing Date: December 19, 2000
Examiner: Unknown Group Art Unit: 2877
Docket No.: M-10700 US

San Jose, California
August 27, 2001

COMMISSIONER FOR PATENTS
Washington, D. C. 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

A search was conducted in August 2000 and a copy of the results is being submitted herewith.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made, other than as described above; or

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3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on August 27, 2001.

T. L. Kaplan 8/27/01
Tammy L. Kaplan Date of Signature

Respectfully submitted,

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U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-10700 US		09/741,663	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					ANDREI V. SHCHEGROV			
					Filing Date		Group	
					December 19, 2000		2877	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,963,329	10/5/99	Conrad et al.	356	372	10/31/97	
	AB							
	AC							
	AD							
	AE							
	AF							
	AG							
	AH							
	AI							
	AJ							
	AK							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ	Patent Search conducted on August 1, 2000						
	AR	"Ultraviolet-visible ellipsometry for process control during the etching of submicrometer features," N. Blayo et al., <i>J. Opt. Soc. Am. A</i> , Vol. 12, No. 3, March 1995, pp. 591-599						
	AS	"Algorithm Implementation and Techniques for Providing More Reliable Overlay Measurements and Better Tracking of the Shallow Trench Isolation (STI) Process," D. Schramm et al., <i>SPIE: Conference on Metrology, Inspection, and Process Control of Microlithography XIII</i> , March 1999, pp. 116-122						
Examiner			Date Considered					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								